

Optical Measurement of Surface Topography

Richard Leach (Ed.)

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Editor

Prof. Richard Leach
National Physical Laboratory
(NPL)
Industry & Innovation Div.
Hampton Road
TW11 0LW Teddington, Middx.
United Kingdom
E-mail: richard.leach@npl.co.uk

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Preface

The measurement and characterisation of areal surface topography is becoming crucial to many modern manufacturing methods. The control of areal surface structure allows a manufacturer to radically alter the functionality of a part. Examples include structuring to effect fluidics, optics, tribology, aerodynamics and biology. To control such manufacturing methods requires appropriate measurement strategies. There is also soon to be the introduction of a series of ISO specification standards in this area and this book will become a companion guide to these standards. These new standards are many and complex, as are the new measurement techniques, so industry will hopefully benefit from such a book.

There is now a wealth of new optical techniques on the market, or being developed in academia, that can measure areal surface topography. Each method has its strong points and limitations. This book will start with introductory chapters on optical instruments, their common language, generic features and limitations, and their calibration. Each type of modern optical instrument will then be described (in a common format) by experts in the field.

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This book is dedicated to the first engineer I ever met and the one that I want to please the most – thanks dad!

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